

Title (en)  
Spin-coating apparatus for preparing optical discs

Title (de)  
Vorrichtung zur Schleuderbeschichtung zur Beschichtung von optischen Speicherplatten

Title (fr)  
Appareil de revêtement par centrifugation pour le revêtement de disques optiques

Publication  
**EP 0920920 A3 20001227 (EN)**

Application  
**EP 98309940 A 19981204**

Priority  
JP 35240697 A 19971204

Abstract (en)  
[origin: EP0920920A2] A spin-coating apparatus (10) for preparing optical discs (1) is composed of an applying device equipped with a nozzle (12) having a pointed end for giving a coating liquid onto a disc substrate (1), a rotatable spinner head (13) for keeping the substrate (1) horizontally, a round guard wall (15) provided around the spinner head (13) which has an opening (16) on its top and keeps the applied coating liquid within the guard wall (15), and an air exhaust system (18), wherein the nozzle (12) has a surface of polytetrafluoroethylene at least at the pointed end and on an inside and outside walls following the pointed end at a length of 1 mm or more. <IMAGE>

IPC 1-7  
**B05C 11/08**

IPC 8 full level  
**B05C 11/08** (2006.01); **B05D 1/40** (2006.01); **G11B 7/26** (2006.01)

CPC (source: EP)  
**B05C 11/08** (2013.01)

Citation (search report)

- [XY] US 5143552 A 19920901 - MORIYAMA MASAHI [JP]
- [Y] GB 2088748 A 19820616 - GUSMER CORP
- [X] US 5002008 A 19910326 - USHIJIMA MITSURU [JP], et al
- [A] WO 9526237 A1 19951005 - SIEMENS AG [DE], et al
- [A] PATENT ABSTRACTS OF JAPAN vol. 018, no. 525 (C - 1257) 5 October 1994 (1994-10-05)

Designated contracting state (EPC)  
AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE

DOCDB simple family (publication)  
**EP 0920920 A2 19990609; EP 0920920 A3 20001227; EP 0920920 B1 20030507**; DE 69814315 D1 20030612; DE 69814315 T2 20040122;  
JP H11165115 A 19990622

DOCDB simple family (application)  
**EP 98309940 A 19981204**; DE 69814315 T 19981204; JP 35240697 A 19971204